EP 0 681 316 A3

(12)

## **EUROPEAN PATENT APPLICATION**

(88) Date of publication A3: 07.01.1998 Bulletin 1998/02

(51) Int. Cl.<sup>6</sup>: **H01L 21/20** 

(11)

(43) Date of publication A2:08.11.1995 Bulletin 1995/45

(21) Application number: 95106505.1

(22) Date of filing: 28.04.1995

(84) Designated Contracting States: **DE FR GB** 

(30) Priority: 02.05.1994 JP 116007/94 27.09.1994 JP 257616/94

(71) Applicant: SONY CORPORATION Tokyo (JP)

(72) Inventors:

 Ino, Masumitsu, c/o Sony Corp. Tokyo (JP)

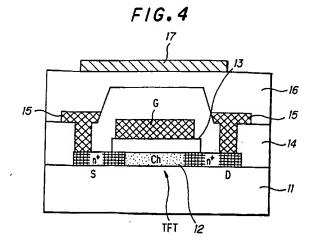
 Hayashi, Hisao, c/o Sony Corp. Tokyo (JP)

 Kunii, Masafumi, c/o Sony Corp. Tokyo (JP)

- Urazono, Takenobu, c/o Sony Corp.
   Tokyo (JP)
- Nishihara, Shizuo, c/o Sony Corp. Tokyo (JP)
- Minegishi, Masahiro, c/o Sony Corp. Tokyo (JP)
- (74) Representative:
  Müller, Frithjof E., Dipl.-Ing.
  Patentanwälte
  MÜLLER & HOFFMANN,
  Innere Wiener Strasse 17
  81667 München (DE)

## (54) Method of processing a thin film on a substrate for display

(57)In a method of manufacturing semiconductor chips for display, a semiconductor thin film is first formed on an insulating substrate, and then a series of processes containing a heat-treatment process for the semiconductor thin film are carried out to form integrated thin film transistors on a sectioned area for one chip. Thereafter, pixel electrodes for one picture (frame) are formed within the sectioned area. During the series of processes, a laser pulse is irradiated onto the sectioned area by one shot to perform a heat treatment on the semiconductor thin film for one chip collectively and simultaneously (i.e., perform a batch heat treatment on the semiconductor thin film). Through the batch heat treatment, the crystallization of the semiconductor thin film is promoted. In addition, after the semiconductor thin film is doped with impurities, the activation of impurities doped in the semiconductor thin film can be performed by the batch heat treatment.



EP 0 681 316 A3



## **EUROPEAN SEARCH REPORT**

Application Number EP 95 10 6505

		ERED TO BE RELEVANT		
Category	Citation of document with i of relevant pass	ndication, where appropriate, ages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Ci.6)
Α		F JAPAN (E-462), 9 December 1986 (RICOH CO LTD), 24 July	1	H01L21/20
A	1993	JAPAN (E-1323), 22 February (JII TEI SHII:KK), 7	1	
A,D		F JAPAN (P-1576), 20 July 1993 (SONY CORP), 19 March	1	
				TECHNICAL FIELDS SEARCHED (Int.CI.6) H01L B23K
:				
		•		
	The present search report has	been drawn up for all claims		
	Place of search THE HAGUE Date of completion of the search 3 November 1997		Sch	Examiner nuermans, N
X : parti Y : parti docu A : tech O : non	ATEGORY OF CITED DOCUMENTS ioularly relevant if taken alone cutarly relevant if combined with anotiment of the same category nological background written disclosure mediate document	T: theory or principl E: earlier patent do: after the filing dat her D: document cited ii L: document oited for a: member of the si	e underlying the issument, but publice in the application or other reasons	nvention shed on, or